KMLabs

EUV Source Developments

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The Leader In Ultrafast

Founded in 2003 by award-winning scientists in ultrafast laser technology, KMLabs continues its legacy of innovation.

- 1st cryogenically-cooled ultrafast lasers
- 1st robust 10 femtosecond lasers
- 1st bright tabletop coherent EUV and soft X-ray beams
- >20 Patents
- 12 Science papers; 3 Nature papers; 6 Nature Photonics papers





Pantheon[™] EUV Source

- RAEA™: Ultrafast Ti:Sapphire IR Laser
 - 800 nm 35 fs pulses
- **XUUS™ :** High Harmonic Generator
 - 28nm and 13.5nm
 - In demand for semiconductor applications
- Arterium™ :
 - Vacuum Beamline
 - Modular components for EUV delivery



XUUS[™] 5 High Harmonic Generator

The new XUUS 5 from KMLabs brings more stability and more flux to high harmonic generation of coherent EUV light in a tabletop form factor.



Unique XUUSTM Features

- Waveguide architecture permits better gas control and conversion efficiency
- Cartridge-mounted waveguide for ease of maintenance
- Produces coherent femtosecond EUV pulses







Performance

Improved flexibility, stability, and flux

4 systems delivered so far this year





Wavelength Range (for ~800nm pump)	~10 – 50nm
Flux	Up to 10 ¹² ph/s/harmonic
Power stability of single harmonic	5% RMS
Dimensions (mm)	1200 L x 330 W x 176 H)







Robust Driving Laser Options

- Tested successfully with leading ultrafast lasers
- More flexibility
 - Maximize EUV flux with KMLabs RAEA with cryocooling
 - Strong per pulse performance with other popular lasers
 - Yb-based option offers high rep rates and stability up to 40 eV





Applications



Imec Collaboration

Joint development with imec is advancing semiconductor applications of the KMLabs EUV source

- Pump probe spectroscopy
- Interference lithography (IL)
- Coherent diffractive imaging (CDI)



XUUS 4: Two XUUS beamlines



IL Progress

- Successful initial proofs of concept for the KMLabs IL system
- Further implementation this year will push the limits of high-NA patterning









https://www.imec-int.com/en/press/imec-demonstrates-20nm-pitch-linespace-resist-imaging-high-na-euv-interference-lithography

Coherent Diffractive Imaging

- HHG EUV source is ideally suited to actinic mask imaging
- Near the $\lambda/2$ resolution limits
- Development focused on detector speed and data processing

Demonstrations of results published in 2021

- Modeling interface roughness Esashi et al. "Influence of surface and interface roughness on X-ray and extreme ultraviolet reflectance: A comparative numerical study." *OSA Continuum* **4**, 1497 (2021)
- Detecting defects with OAM light Wang et al. "Coherent Fourier scatterometry using orbital angular momentum beams for defect detection." *Optics Express* **29**, 3342 (2021)
- Reflectometer using IMEC sample Tanksalvala et al. ""Nondestructive, high-resolution, chemically specific 3D nanostructure characterization using phase-sensitive EUV imaging reflectometry," Science Advances 7, eabd9667 (2021)



Spatially resolved, composition-sensitive, 3D nanostructure characterization

Amplitude- and phase-sensitive imaging reflectometer





Tanksalvala et al., Sci. Adv. 2021; 7 : eabd9667 27 January 2021

Thank You

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